



Design, Fabrication, Testing of MEMS/NEMS

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Deadline for manuscript
submissions:

closed (30 December 2022)

Message from the Guest Editors

Dear Colleagues,

Here, we would like to introduce the special issue of "Design, Fabrication, Testing of MEMS/NEMS" and encourage our colleagues to contribute their excellent work to this Special Issue. This Special Issue aims to highlight recent novel progresses in cutting-edge MEMS device technologies, including original research articles and topical reviews in the scope of materials, design and fabrication technologies, characterization methods, packaging and microsystem integration solutions.

The topics of this Special Issue include, but are not limited to:

1. Novel functional MEMS materials;
2. Innovative MEMS mechanical and chemical sensors;
3. Biological devices for wearable healthcare systems;
4. Optical and quantum MEMS devices and systems;
5. RF MEMS for telecommunication systems;
6. MEMS devices for self-powered systems;
7. Micro/nano fabrication process and integration;
8. MEMS packaging and reliability issues.





Editor-in-Chief

Message from the Editor-in-Chief

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